

The Rika™ Source Plasma System may be covered by one or more of the following patents:

| Country                    | Pat. No.        |
|----------------------------|-----------------|
| Australia                  | 2018254601      |
| Australia                  | 2022287568      |
| China                      | ZL2023300225363 |
| China                      | CN110709118     |
| Colombia                   | 40710           |
| European Patent Convention | 3860677         |
| European Patent Convention | EP3860676       |
| India                      | 458159          |
| Japan                      | 7654053         |
| Japan                      | 7465329         |
| Japan                      | 1751385         |
| Japan                      | 1746549         |
| Japan                      | 1751427         |
| Japan                      | 7189150         |
| Mexico                     | 416520          |
| Russian                    | 2807435         |
| Singapore                  | 11201909722W    |
| South Korea                | 10-2574345      |
| United States              | 11980707        |
| United States              | 11925743        |
| United States              | 10758664        |
| United States              | 10758665        |
| United States              | D1044029        |
| United States              | D1044030        |
| United States              | 10960128        |
| United States              | 11013851        |
| United States              | 11090425        |
| United States              | 11103629        |
| United States              | 11103630        |
| United States              | 11110217        |
| United States              | D1021953        |
| United States              | D1033455        |
| United States              | D1033468        |
| United States              | D1048411        |
| Vietnam                    | 40189           |